

26  
b  
"According to the third embodiment that has been described, the pressure controller 40 controls the suction pump according to the position of the plunger 12 detected by the position sensor 14. It is also possible to arrange for the pressure controller 40 to control the suction pump according to time counted by the timer 42a shown in Figs. 4(a)-4(d)."

**In the Claims**

Applicants elect Species A including claims 7-12 as directed to a method for manufacturing semiconductor devices, for further prosecution in the present application.

This election is without traverse.

Please cancel claims 13-21 without prejudice or disclaimer of the subject matter contained therein.